Rika™ Source Plasma System

Country	**Pat. No.**
Australia	2018254601
China	ZL2023300225838
China	CN110709118
Colombia	40710
European Patent Convention	3860677
European Patent Convention	EP3860676
India	458159
Japan	7465329
Japan	1751385
Japan	1746549
Japan	1751427
Japan	7189150
Russian	2807435
South Korea	10-2574345
United States	11980707
United States	11925743
United States	10758664
United States	10758665
United States	10960128
United States	11013851
United States	11090425
United States	11103629
United States	11103630
United States	11110217
United States	D1021953
United States	D1033455
United States	D1033468
Vietnman	40189

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